

ABSTRACT

LASER PROCESSING APPARATUS

A laser beam irradiating mechanism of a laser processing apparatus includes: a pulsed laser oscillator configured to oscillate a pulsed laser beam; a condenser configured to condense the laser beam oscillated from the pulsed laser oscillator, and irradiate a workpiece held on a chuck table with the condensed laser beam; a polygon mirror disposed between the pulsed laser oscillator and the condenser, and having a plurality of mirrors arranged concentrically with respect to a rotating shaft, the plurality of mirrors dispersing the pulsed laser beam oscillated from the pulsed laser oscillator; and a guiding unit disposed between the pulsed laser oscillator and the polygon mirror, the guiding unit guiding the pulsed laser beam such that the pulsed laser beam is not applied to an angular portion of mirrors adjacent to each other. (Figure 2)